

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Antonio L. P. Rotondaro

Serial No: 10/001,483

Examiner: Michellé Estrada

Filed: 11/01/2001

For: METHOD TO IMPROVE THE UNIFORMITY AND REDUCE THE SURFACE ROUGHNESS  
OF THE SILICON DIELECTRIC INTERFACE



Docket No: TI-1111  
Conf. No: 1900  
Art Unit: 282

AF/2800  
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AMENDMENT PURSUANT TO 37 CFR 1.116

Assistant Commissioner for Patents  
Washington, DC 20231

MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on 1-10-03.

Ann Trent  
Ann Trent

Dear Sir:

✓  
Responsive to the Office Action mailed November 20, 2002, in connection with the above-identified application, Applicant respectfully submits the following amendments and remarks.

Please  
enter  
ME  
1/28/03